EAST Search History

EAST Search History (Prior Art)

Ref#	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L3	206	(applied materials).as. and (((lookup or (look adj up)) adj table) or (bin with table) or (bin with algorithm))	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 08:10
L4	98	(applied materials).as. and ((bin\$4 with table) or (bin\$4 with algorithm) or (bin\$4 with method))	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 08:28
L5	2	"4345312".pn.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 08:43
L6	208	(applied materials).as. and (((lookup or (look adj up)) adj table) or (bin with table) or (bin\$4 with algorithm))	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 08:47
L7	30744	(wafer or semiconductor) and ((bin\$4 with table) or (bin\$4 with algorithm) or (bin\$4 with method))	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 08:56
L8	2493	(wafer or semiconductor) and ((bin\$4 with table) or (bin\$4 with algorithm) or (bin\$4 with method)) and (trim\$4)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 08:56
L9	191	(wafer or semiconductor) and ((bin\$4 with table) or (bin\$4 with algorithm) or (bin\$4 with method)) and (trim\$4 with value)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 09:08
L27	2408	(700/121).cds.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 10:38
L28	1	"20020175384"	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/30 10:52
S1	17685	(TOKYO same ELECTRON). as.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/24 09:19

S2	3449	((TOMOYASU same MASAYUKI) or (FUNK MERRITT LANE) or (PINTO KEVIN AUGUSTINE) or (ODACIFI MASAYA) or (CHEN LENUEL) or (YAMASHITA ASAO) or (IWAMI AKIRA) or (TAYAHASHI HIROYUKI)).in.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/24 09:22
S4	1	"20040185583"	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/24 11:53
S5	8	10/229,446	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/24 14:08
S6	2	"20030045131"	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/24 14:10
S7	0	METHODS AND APPARATUS FOR PROCESSING MICROELECTRONIC WORKPIECES USING METROLOGY	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/24 14:12
S8	2	(METHODS APPARATUS PROCESSING MICROELECTRONIC WORKPIECES USING METROLOGY).ti.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/24 14:12
S9	7	60/454,597	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/24 14:14
S10	6	("10705201" or "10705200" or "10704969" or "10705397")	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/24 15:38
S11	161	(TOKYO same ELECTRON). as. and metrology.clm.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/24 16:22

S12	30	[("4659220"] "4869593"] "4899055" "5042949"] "5191393" "5258823" "5291269"] "5486701"] "5517032" "5604344" "5616063" "56956011 "5747813" "5757502" "5825498" "5835225" "5872633" "5943122" "5942203" "5945742" "6052188" "6108091" "6108002" "6111634" "6120348" "6142855" "6157450" "6149894"	US-PGPUB; USPAT; USOOR	OR	OFF	2009/09/24 16:29
S13	1132033	WO "03021642"	US-PGPUB; USPAT; USOCR	OR	OFF	2009/09/24 16:32
S17	74	verbeke.in.	US-PGPUB; USPAT; USOOR	ADJ	OFF	2009/09/24 16:32
S18	16	verbeke.in. and WO	US-PGPUB; USPAT; USOOR	ADJ	OFF	2009/09/24 16:32
S19	113	verbeke.in.	US-PGPUB; USPAT; USOOR; EPO	ADJ	OFF	2009/09/24 16:34
S21	2	(WO "3021642") or (WO "204887") or (WO "2004084280")	US-PGPUB; USPAT; USOOR; EPO	ADJ	OFF	2009/09/24 16:36
S22	1	(WO "3021642") or (WO "204887") or (WO "4084280")	US-PGPUB; USPAT; USOOR; EPO	ADJ	OFF	2009/09/24 16:36
S23	2	(WO "3021642") or (WO "0204887") or (WO "2004084280")	US-PGPUB; USPAT; USOOR; EPO	ADJ	OFF	2009/09/24 16:36
S24	2	(WO "3021642") or (WO "204887") or (WO "2004084280")	US-PGPUB; USPAT; USOOR; EPO	ADJ	OFF	2009/09/24 16:38
S25	3	("6165805" "6438441" "5240556").pn.	US-PGPUB; USPAT; USOOR; EPO	ADJ	OFF	2009/09/24 16:48
S26	949	(TOKYO same ELECTRON). as. and (metrology or measur\$3).clm.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/24 17:23
S27	7	"6960416"	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/24 18:22

S28	245	(control and (strategy and plan) and recipe) and semiconductor	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/25 16:53
S29	1	oxidized Tunable Etch Resistant ARC (TERA)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/25 17:09
S30	2543	oxidized Tunable Etch Resistant ARC or (TERA)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/25 17:09
S31	2543	(oxidized Tunable Etch Resistant ARC) or (TERA)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/25 17:09
S32	1	(oxidized Tunable Etch Resistant ARC)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/25 17:09
S34	59	(Tunable Etch Resistant ARC) or (tera material)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/25 17:11
S35	315	wall heating (element or lamp or apparatus)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/28 16:44
S36	12	wall heating (element or lamp or apparatus) and wafer	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/28 16:51
S37	5506	(TOKYO same ELECTRON). as. and pressure	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 07:53
S38	876	(TOKYO same ELECTRON). as. and (low adj pressure)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 07:53
S39	112	(TOKYO same ELECTRON). as. and (low adj pressure with ("10" or "100" or "75"))	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 07:54
S40	49	(TOKYO same ELECTRON). as. and (low adj pressure with ("10" or "100" or "75")) and mtorr	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 07:55
S42	32365	(low adj pressure) with process\$3	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 08:00

S43	42	(TOKYO same ELECTRON). as. and (low adj pressure with ("10" or "100" or "75")) and mtorr and temperature	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 08:01
S44	23	(TOKYO same ELECTRON). as. and (low adj pressure with ("10" or "100" or "75")) and mtorr and (temperature with gas)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 09:37
S45	53295	temperature process gas	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	WITH	OFF	2009/09/29 09:44
S46	1213	(TOKYO same ELECTRON). as. and S45	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 09:44
S50	231	(TOKYO same ELECTRON). as. and S45 and (distribution system)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	WITH	OFF	2009/09/29 09:45
S51	75	(thermal treatment chamber) and (temperature with ("10" or "50"))	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 09:58
S52	4	US-6284086-\$.DID. OR US- 4838978-\$.DID. OR WO- 0178517-\$.DID. OR US- 4492618-\$.DID. OR US- 5273588-\$.DID.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 10:40
S53	3	US-6284006 -\$.DID. OR US- 4838978-\$.DID. OR WO- 0178517-\$.DID. OR US- 4492610-\$.DID. OR US- 5273588-\$.DID. OR 2002/195201 OR 2002/802947 OR US- 5273588-\$.DID. OR 2002/811216	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 10:47
S54	125	"6284006" OR "4838978" OR WO-0178517 OR "4492610" OR "5273588" OR 2002/195201 OR 2002/802947 OR "5273588" OR WO-2002/811216	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 10:49
S55	125	"6284006" OR "4838978" OR (WO-0178517) OR "4492610" OR "5273588" OR 2002/195201 OR 2002/802947 OR "5273588" OR (WO-2002/811216)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 10:49

S56	4	("6284006" OR "4838978" OR (WO-0178517) OR "4492610" OR "5273588" OR 2002/195201 OR 2002/802947 OR "5273588" OR (WO-2002/811216)).pn.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 10:50
S57	55	(thermal treatment chamber) and (low with temperature)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 10:55
S58	22	"5240556"	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 11:02
S59	347	((Ishikawa Yoshio) or (arami Junichi) or (Ikeda Towl) or (Iwata Teruo)).in.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 11:06
S60	3038366	temperature	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 11:06
S61	95	S59 and S60	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 11:07
S62	1	"5484483" .pn.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 11:16
S63	53	"5221403"	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 11:21
S64	53	"5,221,403"	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 11:44
S 65	0	eric strang	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 13:24
S66	120	(eric same strang).in.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 13:24
S67	2	"20030045131" and (temperature and gas)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 14:35

S68	1769	gas distribution system and temperature	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 14:46
S69	1481	gas distribution system and temperature and (wafer or chamber or semiconductor)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 14:50
S70	521	((gas distribution system) same temperature) and (wafer or chamber or semiconductor)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 14:58
S71	726	((thermal treatment chamber) or (process space same chamber) and (temperature)) and (wafer or substrate or workpiece or (work piece))	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 16:03
S72	726	((thermal treatment chamber) or (process space same chamber) and (temperature)) and (wafer or substrate or workpiece or (work piece))	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 16:03
S73	3	US-4898798-\$.DID. OR US- 5303671-\$.DID. OR US- 5254505-\$.DID. OR US- 438785D-\$.DID.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 16:24
S74	5	US-6544380-\$.DID. OR US- 5634551-\$.DID. OR US- 6616767-\$.DID. OR US- 1912152-\$.DID. OR US- 6515261-\$.DID.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 16:29
S75	72	thermal treatment chamber with temperature	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 16:44
S76	1	"20040185583".pn.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 17:08
S77	10	US-6884734-\$.DID. OR US-6826843-\$.DID. OR US-20040191998-\$.DID. OR US-4881300-\$.DID. OR US-20050227494-\$.DID. OR US-20040097047-\$.DID. OR US-20040103563-\$.DID. OR US-122004D-\$.DID. OR US-20040110354-\$.DID. OR US-20040110354-\$.DID. OR US-20040110354-\$.DID. OR US-2082925-\$.DID.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 17:11

S78	8021	trim\$4 with amount	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 17:18
S79	0	determin43 same trim\$4 with amount	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 17:18
S80	997	determin\$3 same trim\$4 with amount	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 17:19
S81	367	determin\$3 same trim\$4 with amount and (wafer or substrate or workpiece or (work piece) or semiconductor)	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	ADJ	OFF	2009/09/29 17:19
S82	2	"20030045131"	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	OR	OFF	2009/09/29 18:01
S83	5	US-5769952-\$,DID. OR US- 5368054-\$,DID. OR US- 6745637-\$,DID. OR US- 6267122-\$,DID. OR US- 20010024691-\$,DID.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/29 18:58
S84	3	US-5672239-\$.DID. OR US- 5776360-\$.DID. OR US- 6467491-\$.DID. OR EP- 0998170-\$.DID.	US-PGPUB; USPAT; EPO; JPO; IBM_TDB	SAME	OFF	2009/09/29 19:01

EAST Search History (Interference)

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9/30/2009 11:22:40 AM

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